INFORMATION DISCLOSURE CITATION (Use several sheets (f necessary)

Docket Number (Optional) TWI-12730 Applicant(s)	Application Number 89,332
Minna Hovienen et al_	
Filing Date	Group Art Unit Unknown 2872
HEREWITH	Vaknows 16/6

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	Ref	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
MI	*AA	4,522,510	06/11/1985	Rosencwaig et al.	374	7	04/01/1983
- / - / -	*AB	4,636,088	01/13/1987	Rosencwaig et al.	374	5	05/21/1984
	*AC	4,710,030	12/01/1987	Tauc et al.	356	432	05/17/1985
	•AD	4,854,710	08/08/1989	Opsal et al.	356	432	07/23/1987
	•AE	4,999,014	03/12/1991	Gold et al.	356	382	05/04/1989
	•AF	5,074,669	12/24/1991	Opsal	356	445	12/12/1989
	*AG	5,181,080	01/19/1993	Fanton et al.	356	381	12/23/1991
	*AH	5,298,970	03/29/1994	Takamatsu et al.	356	349	10/01/1992
	•AI	5,973,787	10/26/1999	Aspnes et al.	356	369	05/12/1998
	*AJ	5,978,074	11/02/1999	Opsal et al.	356	72	07/03/1997
	•AK	6,052,188	04/18/2000	Fluckiger et al.	356	369	07/08/1998
	*AL	6,081,330	06/27/2000	Nelson et al.	356	318	09/18/1998
	*AM	6,268,916	07/31/2001	Lee et al.	356	369	05/11/1999
	*AN	6,512,815	01/28/2003	Opsal et al.	378	89	05/06/2002
	•AO	6,535,285	03/18/2003	Opsal et al.	356	369	02/08/2000

FOREIGN PATENT DOCUMENTS

DOCUMENT				Γ			TRANSLATION	
1	REF	NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	YES	No
w	•AP	WO 99/02970	01/21/1999	PCT	GOIN	21/21		
1	•A0	WO 00/68656	11/16/2000	PCT	G013	4/00		

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

m	*AR	L. Zhou et al., "Use of a New Thermal Wave Technology for Ultra-Shallow Junction Implant Monitoring," Proceedings of the X International Conference on Ion Implantation Technology, June 1998, Kyoto (Japan), pp. 1-4.
7	*AS	A. Salnick et al., "Quantitative Photothermal Characterization of Ion-Implanted Layers in Si," 25th Review of Progress in QNDE, Snowbird (Utah), July 19-24, 1998, pp. 1-15.
	*AT	U.S. Patent Application No. 09/499,974, filed February 8, 2000, entitled "Combination Thermal Wave and Optical Spectroscopy Measurement System,". (5 drawing pages included) by Jon Opsal et al., 29 pages in length.
7-1		

Examiner	SIKDER	Date Considered		· •	04			
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 699; Draw line through citation if								
not in conformance and not considered. Include copy of this form with next communication to applicant.								

Modified Form PTO-A820 (also form PTO-1449)

Sheet 1 of 1